

Resource Summary Report

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Rigaku: TXRF 3760

RRID:SCR_020478

Type: Tool

Proper Citation

Rigaku: TXRF 3760 (RRID:SCR_020478)

Resource Information

URL: <https://www.rigaku.com/products/semi/txrf3760>

Proper Citation: Rigaku: TXRF 3760 (RRID:SCR_020478)

Description: Surface contamination metrology. Used to measure elemental contamination at discrete points or with full wafer maps.

Resource Type: instrument resource

Keywords: Rigaku, Semiconductor Metrology, Instrument Equipment, USEDit,

Availability: Commercially available

Resource Name: Rigaku: TXRF 3760

Resource ID: SCR_020478

Alternate IDs: Model_Number_TXRF 3760

Record Creation Time: 20220129T080350+0000

Record Last Update: 20260912T195937+0000

Ratings and Alerts

No rating or validation information has been found for Rigaku: TXRF 3760.

No alerts have been found for Rigaku: TXRF 3760.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We have not found any literature mentions for this resource.